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PTO/SB/21 (08-03)

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Application Number	10/735,110
Filing Date	December 12, 2003
First Named Inventor	Pawan K. Nimmakayala
Art Unit	Unassigned
Examiner Name	Unassigned
Attorney Docket Number	P122/MII-94-69v18

ENCLOSURES (Check all that apply)

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Form 1449 - IDS
Eighteen (18) References
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Remarks

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Firm or Individual name	Law Office of Kenneth C. Brooks
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Nimmakayala et al. PATENT APPLICATION
Serial No.: 10/735,110 Group Art Unit: Unassigned
Filing Date: December 12, 2003 Examiner: Unassigned
For: MAGNIFICATION CORRECTION EMPLOYING OUT-OF-PLANE
DISTORTION OF A SUBSTRATE

INFORMATION DISCLOSURE STATEMENT

Commissioner
for Patents
Alexandria, VA 22313

Sir:

The following information is submitted in compliance
with Applicants' duty of disclosure under 37 C.F.R. § 1.56.

Form PTO-1449 and a copy of each reference recited below
accompanies this document. It is respectfully requested that
the cited information be expressly considered during the
prosecution of this application, and the references be made
of record therein and appear among the "references cited" on
any patent to issue therefrom.

ISSUED PATENTS

<u>Patent Number</u>	<u>Inventor</u>	<u>Grant Date</u>
5,669,303	Maracas et al.	09/23/1997
6,334,960	Willson et al.	01/01/2002
6,696,220	Bailey et al.	02/24/2004

PENDING PATENT APPLICATIONS

<u>Serial Number</u>	<u>Inventor</u>	<u>Filing Date</u>
10/136,188	Voisin	05/01/2002
10/194,414	Sreenivasan et al.	07/11/2002
10/194,991	Sreenivasan et al.	07/11/2002
10/293,224	Choi et al.	11/13/2002

10/293,919	Voisin	11/13/2002
10/316,963	Choi et al.	12/11/2002
10/614,716	Choi et al.	07/07/2003
10/788,700	Sreenivasan	02/27/2004

PATENT APPLICATION PUBLICATIONS

<u>Publication No.</u>	<u>Inventor</u>	<u>Publication Date</u>
US 2002/0094496	Choi et al.	07-18-2002
US 2003/0093122	Choi et al.	07-18-2002

FOREIGN PATENT DOCUMENTS

<u>Document Number</u>	<u>Inventor</u>	<u>Pub. Date</u>
WO 01/69317	Montelius et al.	09/20/2001

NON-PATENT DOCUMENTS

Krug, Herbert et al. "Fine Patterning of Thin Sol-Gel Films,"
Journal of Non-Crystalline Solids, 1992, 447-450.

Krauss, et al. "Fabrication of Nanodevices Using Sub-25nm
Imprint Lithography," Appl. Phys. Lett., 67(21), 3114-
3116, 1995.



to M. et al., "Step and Repeat UV-Nanoimprint Lithography: Material Issues," Nanoimprint and Nanoimprint Technology Conference, San Francisco, December 11-13, 2002.

Johnson et al., "Advances in Step and Flash Imprint Lithography," SPIE Microlithography Conference, February 23-28, 2003.

CERTIFICATE OF MAILING

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Signed: Alexis Sheffield

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Date: April 1, 2004

Respectfully,

Kenneth C. Brooks

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Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet

1

of

4

Complete if Known

Application Number

10/735.110

Filing Date

12/12/2003

First Named Inventor

Nimmakayala et al.

Group Art Unit

Unassigned

Examiner Name

Unassigned

Attorney Docket Number

P122/MII-94-69V18

U.S. PATENT DOCUMENTS

[illegible]

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¹Unique citation designation number. ²See attached Kinds of U.S. Patent Documents. ³Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.

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				Application Number	10/735,110
				Filing Date	12/12/2003
				First Named Inventor	Nimmakayala et al.
				Group Art Unit	Unassigned
				Examiner Name	Unassigned
Sheet	3	of	4	Attorney Docket Number	P122/MII-94-69V18

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	C5	KRUG et al., "Fine Patterning of Thin Sol-Gel Films," Journal of Non-Crystalline Solids, 1992, pp. 447-450, vol. 147 & 148.	
	C6	Krauss et al., "Fabrication of Nanodevices Using Sub-25nm Imprint Lithography," Appl. Phys. Lett 67(21), 3114-3116, 1995	
	C7	CHOI et al., "Method and System of Automatic Fluid Dispensing for Imprint Lithography Processes," U.S. Patent Application Publication 2002/0094496. Published on July 18, 2002.	
	C8	CHOI et al., "Methods for High-Precision Gap and Orientation Sensing Between a Transparent Template and Substrate for Imprint Lithography," U.S. Patent Application Publication 2003/0093122. Published on July 18, 2002.	
	C9	VOISIN, "Methods of Manufacturing a Lithography Template," U.S. Patent Application 10/136,188, Filed with USPTO on May 1, 2002.	
	C10	SREENIVASAN et al., "Step and Repeat Imprint Lithography Systems," U.S. Patent Application 10/194,414. Filed with USPTO July 11, 2002.	
	C11	SREENIVASAN et al., "Step and Repeat Imprint Lithography Processes," U.S. Patent Application 10/194,991. Filed with USPTO July 11, 2002.	
	C12	OTTO M. et al., "Step and Repeat UV-Nanoimprint Lithography: Material Issues," Nanoimprint and Nanoprint Technology Conference, San Francisco, December 11-13, 2002.	
	C13	JOHNSON, et al., "Advances in Step and Flash Imprint Lithography," SPIE Microlithography Conference, February 23-28, 2003.	
	C14	CHOI et al., "A Chucking System and Method for Modulating Shapes of Substrates," U.S. Patent Application 10/293,224. Filed with USPTO on November 13, 2002.	
	C15	CHOI et al., "A Method For Modulating Shapes of Substrates," U.S. Patent Application 10/316,963. Filed with USPTO on December 11, 2002.	

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				Application Number	10/735,110
				Filing Date	12/12/2003
				First Named Inventor	Nimmakayala et al.
				Group Art Unit	Unassigned
				Examiner Name	Unassigned
Sheet	4	of	4	Attorney Docket Number	P122/MII-94-69V18

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	C16	VOISIN, "Methods of Inspecting A Lithography Template," U.S. Patent Application 10/293,919. Filed with USPTO on November 13, 2002	
	C17	CHOI et al., "A Conforming Template For Patterning Liquids Disposed On Substrates," U.S. Patent Application 10/614,716. Filed with USPTO on July 7, 2003.	
	C18	SREENIVASAN et al., "Full-Wafer or Large Area Imprinting with Multiple Separated Sub-Fields for High Throughput Lithography," U.S. Patent Application 10/788,700. Filed with USPTO on February 27, 2004.	

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